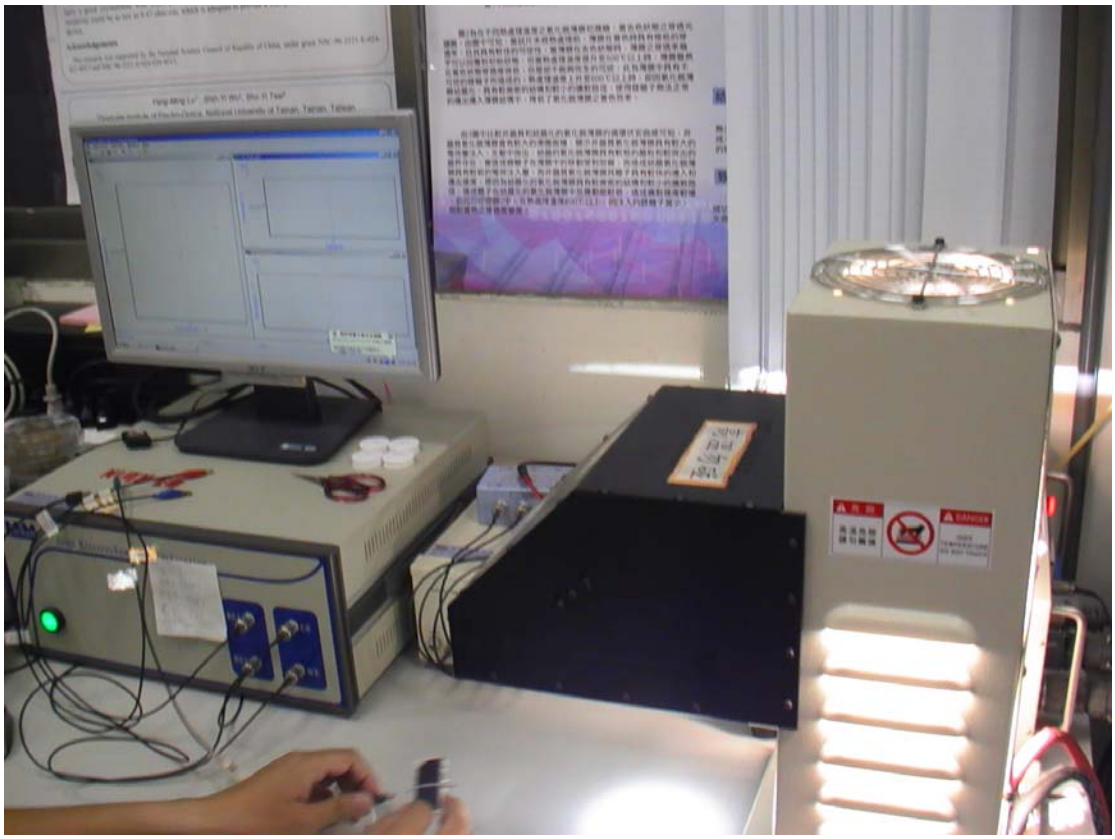
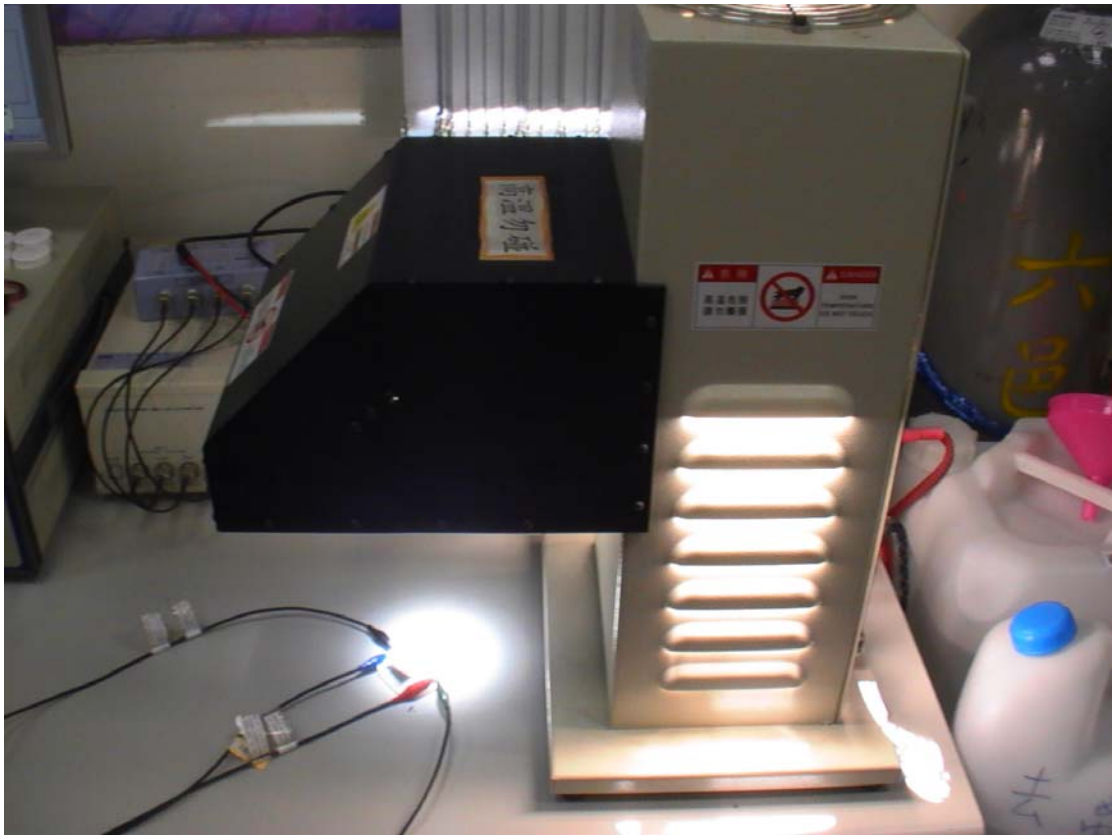
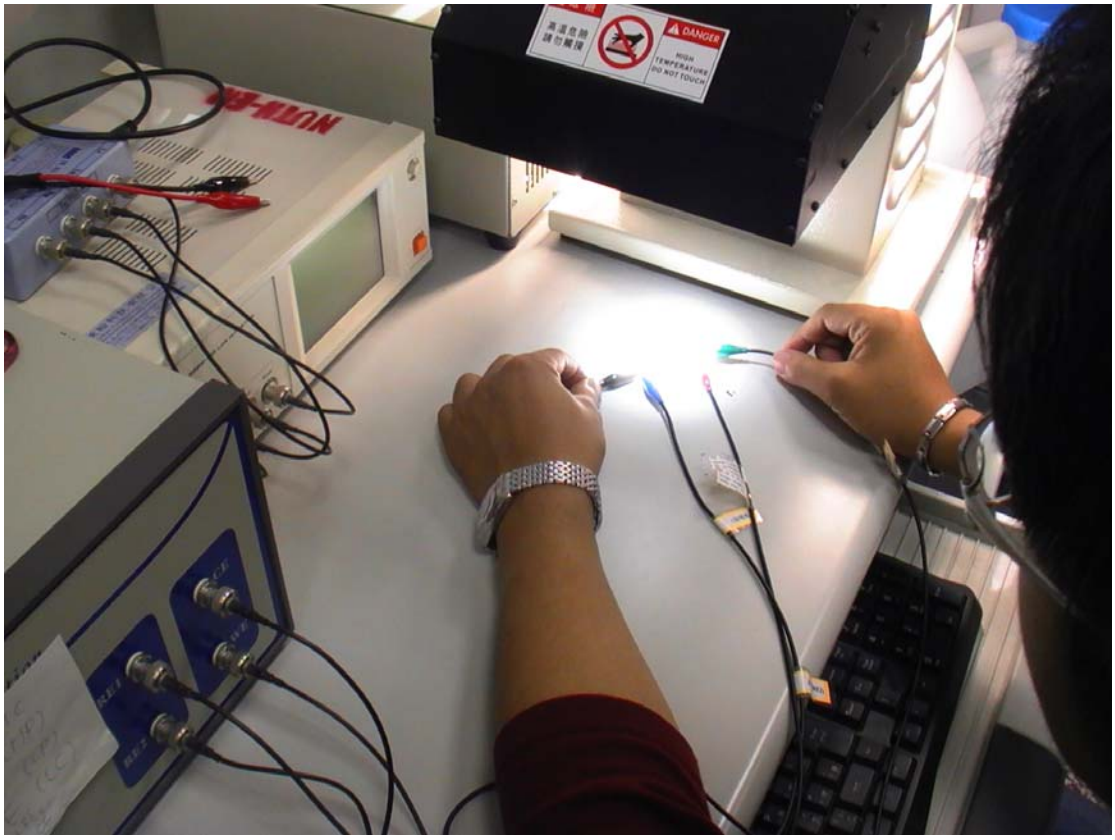
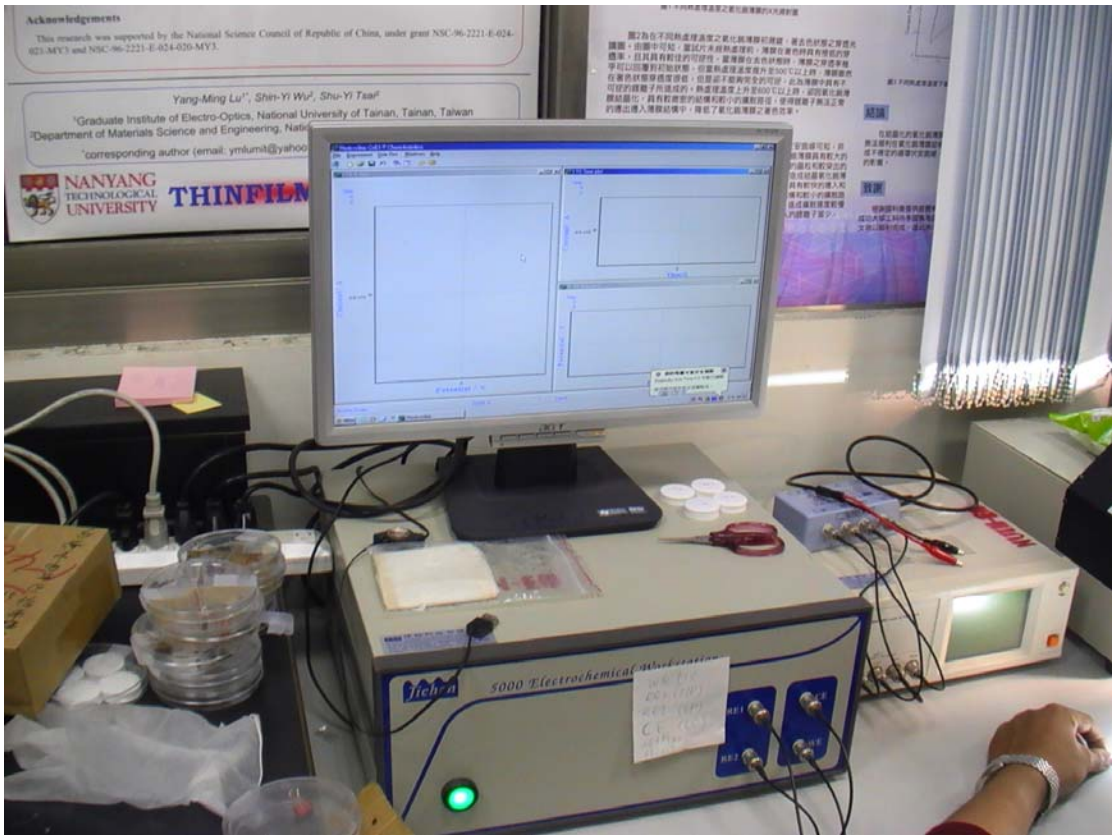





DANGER
HIGH
TEMPERATURE
DO NOT TOUCH


Acknowledgments
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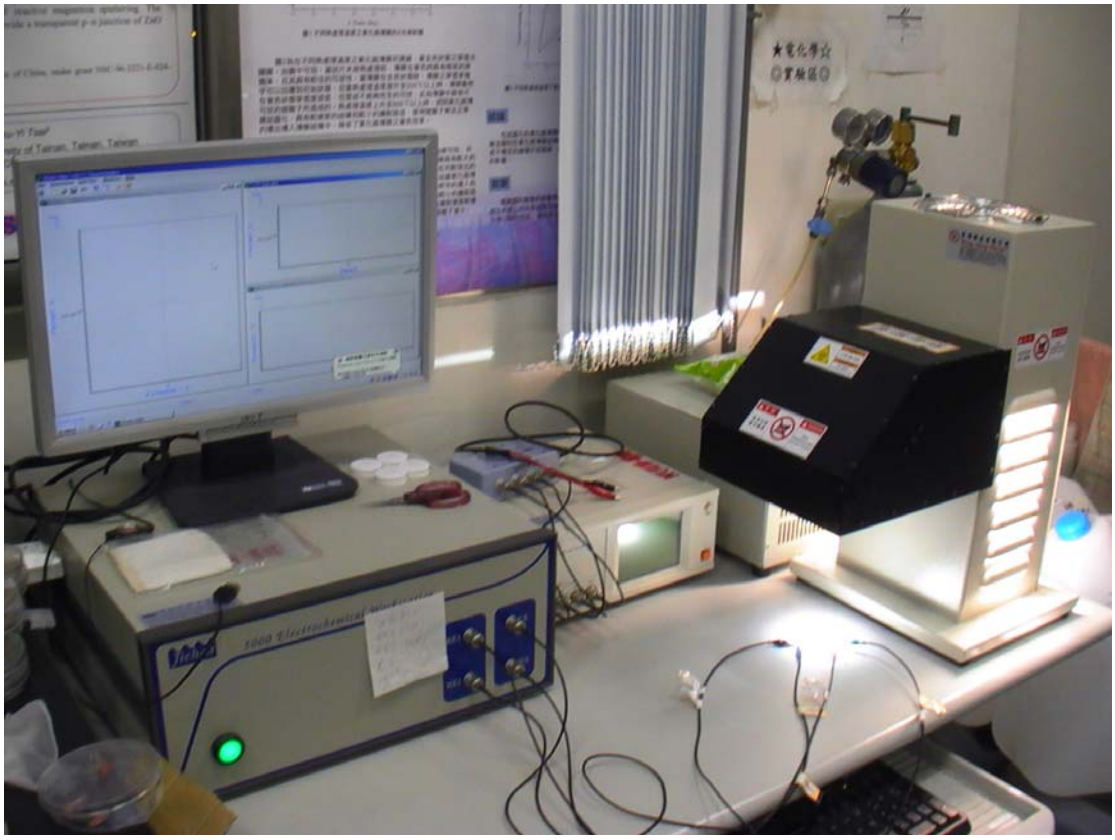
NANYANG TECHNOLOGICAL UNIVERSITY
THINFILM
5000 Electrochemical Workstation


5000 Electrochemical Workstation